

# INTERNATIONAL SEARCH REPORT

International Application No

PCT/FR2004/050433

**A. CLASSIFICATION OF SUBJECT MATTER**  
 IPC 7 G03F7/00 B29C59/04

According to International Patent Classification (IPC) or to both national classification and IPC

**B. FIELDS SEARCHED**

Minimum documentation searched (classification system followed by classification symbols)  
 IPC 7 G03F B29C

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the International search (name of data base and, where practical, search terms used)

EPO-Internal, INSPEC, WPI Data, PAJ, IBM-TDB

**C. DOCUMENTS CONSIDERED TO BE RELEVANT**

Category	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
Y	RUCHHOEFT P ET AL: "Patterning curved surfaces: Template generation by ion beam proximity lithography and relief transfer by step and flash imprint lithography" JOURNAL OF VACUUM SCIENCE AND TECHNOLOGY: PART B, AMERICAN INSTITUTE OF PHYSICS. NEW YORK, US, vol. 17, no. 6, November 1999 (1999-11), pages 2965-2969, XP002206574 ISSN: 0734-211X page 2965 - page 2966; figure 1	1-3,5,7
Y	US 2003/104287 A1 (YUASA MITSUHIRO) 5 June 2003 (2003-06-05) the whole document	1-3,5,7 -/-

Further documents are listed in the continuation of box C.

Patent family members are listed in annex.

\* Special categories of cited documents :

- "A" document defining the general state of the art which is not considered to be of particular relevance
- "E" earlier document but published on or after the International filing date
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- "O" document referring to an oral disclosure, use, exhibition or other means
- "P" document published prior to the International filing date but later than the priority date claimed

"T" later document published after the International filing date or priority date and not in conflict with the application but cited to understand the principle or theory underlying the invention

"X" document of particular relevance; the claimed invention cannot be considered novel or cannot be considered to involve an inventive step when the document is taken alone

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Date of the actual completion of the International search

7 March 2005

Date of mailing of the international search report

18/03/2005

Name and mailing address of the ISA

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C.(Continuation) DOCUMENTS CONSIDERED TO BE RELEVANT		
Category	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
A	DE 199 13 683 A1 (INSTITUT FUER MIKROELEKTRONIK STUTTGART STIFTUNG DES OEFFENTLICHEN REC) 25 November 1999 (1999-11-25) the whole document -----	1-3,5,7
A	US 6 416 908 B1 (JAIN KANTI ET AL) 9 July 2002 (2002-07-09) -----	
A	ROGERS J A ET AL: "Printing, molding, and near-field photolithographic methods for patterning organic lasers, smart pixels and simple circuits" SYNTH. MET. (SWITZERLAND), SYNTHETIC METALS, 1 NOV. 2000, ELSEVIER, SWITZERLAND, vol. 115, no. 1-3, 1 November 2000 (2000-11-01), pages 5-11, XP002279750 ISSN: 0379-6779 -----	
A	US 6 375 870 B1 (VISOVSKY NICK J ET AL) 23 April 2002 (2002-04-23) -----	
A	US 5 281 511 A (GERHARDT JOERGEN) 25 January 1994 (1994-01-25) -----	
A	EP 0 845 710 A (SCHABLONENTECHNIK KUFSTEIN AG) 3 June 1998 (1998-06-03) -----	
A	ROOS N ET AL: "Nanoimprint lithography with a commercial 4 inch bond system for hot embossing" PROCEEDINGS OF THE SPIE - THE INTERNATIONAL SOCIETY FOR OPTICAL ENGINEERING SPIE-INT. SOC. OPT. ENG USA, vol. 4343, 2001, pages 427-435, XP002317296 ISSN: 0277-786X cited in the application -----	

# INTERNATIONAL SEARCH REPORT

Information on patent family members

International Application No

PCT/FR2004/050433

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